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PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10083440	FILING DATE 02/26/2002	CLASS 438	SUBCLASS 14	GAU 2812	EXAMINER Q. HOANG
**APPLICANTS: Ushiki Takeo; Yamada Keizo; Itagaki Yohsuke; Tsujide Tohru; <div style="text-align: center;">2812</div>					
**CONTINUING DATA VERIFIED:					
<p>BEST AVAILABLE COPY</p>					
** FOREIGN APPLICATIONS VERIFIED: JAPAN 2001-58075 03/02/2001					
PG-PUB <input type="checkbox"/>		DO NOT PUBLISH <input type="checkbox"/>		RESCIND <input type="checkbox"/>	
Foreign priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 conditions met <input type="checkbox"/> yes <input type="checkbox"/> no Verified and Acknowledged Examiners's initials				ATTORNEY DOCKET NO NEKW 19.480	
TITLE : Surface contamination analyzer for semiconductor wafers, method used therein and process for fabricating semiconductor device					
<small>U.S. DEPT. OF COMM./PAT. & TM.-PTO-436L (Rev. 12-94)</small>					

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED	
		Total Claims	Print Claim for O.G.
ISSUE FEE		DRAWING	
Amount Due	Date Paid	Sheets Drwg.	Figs. Drwg.
		Print Fig.	
<input type="checkbox"/> TERMINAL DISCLAIMER		Primary Examiner	
		PREPARED FOR ISSUE	
		Application Examiner	
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